



1763

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Gary M. Moore

Assignee: Moore Epitaxial Inc.

Title: METHOD OF CONTROLLING GAS FLOW TO A SEMICONDUCTOR
PROCESSING REACTOR

Serial No.: 09/765,919 Filed: January 18, 2001

Examiner: Unknown Group Art 1763
Unit:

Docket No.: MTEC101001

Monterey, CA
October 23, 2001

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ASSISTANT COMMISSIONER FOR PATENTS
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT
UNDER §1.97(b)

Sir:

Pursuant to 37 C.F.R. §§ 1.56, 1.97 and 1.98, Applicant
wishes to call the following documents (a copy of each is
enclosed) to the attention of the Examiner.

U.S. PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	NAME
1)	6,126,753	10/03/00	Shinriki et al.
2)	5,728,222	03/17/98	Barbee et al.

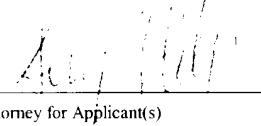
A PTO form 1449 listing these documents is enclosed.

Citation of the above documents shall not be construed as:

1. an admission that the documents are necessarily prior art with respect to the instant invention;
2. a representation that a search has been made, other than as described above; or
3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).

If the U.S.P.T.O. issued a first office action prior to the mailing date of this paper, the Commissioner is hereby authorized to charge any fees required for consideration of this Information Disclosure Statement, and to credit any overpayment of fees to Deposit Account No. 50-0553.

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage for First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231, on October 23, 2001.



Attorney for Applicant(s)

October 23, 2001

Date of Signature

Respectfully submitted,



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